

INTERNATIONAL SEARCH REPORT

International Application No
PCT/FR2004/050433

A. CLASSIFICATION OF SUBJECT MATTER
IPC 7 G03F7/00 B29C59/04

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)
IPC 7 G03F B29C

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the International search (name of data base and, where practical, search terms used)

EPO-Internal, INSPEC, WPI Data, PAJ, IBM-TDB

C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
Y	RUCHHOEFT P ET AL: "Patterning curved surfaces: Template generation by ion beam proximity lithography and relief transfer by step and flash imprint lithography" JOURNAL OF VACUUM SCIENCE AND TECHNOLOGY: PART B, AMERICAN INSTITUTE OF PHYSICS. NEW YORK, US, vol. 17, no. 6, November 1999 (1999-11), pages 2965-2969, XP002206574 ISSN: 0734-211X page 2965 - page 2966; figure 1	1-3,5,7
Y	US 2003/104287 A1 (YUASA MITSUHIRO) 5 June 2003 (2003-06-05) the whole document	1-3,5,7
	----- -/--	

☒ Further documents are listed in the continuation of box C.

☒ Patent family members are listed in annex.

* Special categories of cited documents :

- "A" document defining the general state of the art which is not considered to be of particular relevance
- "E" earlier document but published on or after the International filing date
- "L" document which may throw doubts on priority claim(s) or which is cited to establish the publication date of another citation or other special reason (as specified)
- "O" document referring to an oral disclosure, use, exhibition or other means
- "P" document published prior to the International filing date but later than the priority date claimed

- "T" later document published after the International filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention
- "X" document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone
- "Y" document of particular relevance; the claimed invention cannot be considered to involve an inventive step when the document is combined with one or more other such documents, such combination being obvious to a person skilled in the art.
- "&" document member of the same patent family

Date of the actual completion of the International search

7 March 2005

Date of mailing of the international search report

18/03/2005

Name and mailing address of the ISA

European Patent Office, P.B. 5818 Patentlaan 2
NL - 2280.HV Rijswijk
Tel. (+31-70) 340-2040, Tx. 31 651 epo nl,
Fax: (+31-70) 340-3016

Authorized officer

Haenisch, U

INTERNATIONAL SEARCH REPORT

International Application No

PCT/FR2004/050433

C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT

Category *	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	DE 199 13 683 A1 (INSTITUT FUER MIKROELEKTRONIK STUTTGART STIFTUNG DES OEFFENTLICHEN REC) 25 November 1999 (1999-11-25) the whole document	1-3,5,7
A	US 6 416 908 B1 (JAIN KANTI ET AL) 9 July 2002 (2002-07-09)	
A	ROGERS J A ET AL: "Printing, molding, and near-field photolithographic methods for patterning organic lasers, smart pixels and simple circuits" SYNTH. MET. (SWITZERLAND), SYNTHETIC METALS, 1 NOV. 2000, ELSEVIER, SWITZERLAND, vol. 115, no. 1-3, 1 November 2000 (2000-11-01), pages 5-11, XP002279750 ISSN: 0379-6779	
A	US 6 375 870 B1 (VISOVSKY NICK J ET AL) 23 April 2002 (2002-04-23)	
A	US 5 281 511 A (GERHARDT JOERGEN) 25 January 1994 (1994-01-25)	
A	EP 0 845 710 A (SCHABLONENTEchnik KUFSTEIN AG) 3 June 1998 (1998-06-03)	
A	ROOS N ET AL: "Nanoimprint lithography with a commercial 4 inch bond system for hot embossing" PROCEEDINGS OF THE SPIE - THE INTERNATIONAL SOCIETY FOR OPTICAL ENGINEERING SPIE-INT. SOC. OPT. ENG USA, vol. 4343, 2001, pages 427-435, XP002317296 ISSN: 0277-786X cited in the application	

INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No

PCT/FR2004/050433

Patent document cited in search report		Publication date	Patent family member(s)	Publication date
US 2003104287	A1	05-06-2003	JP 2003173951 A	20-06-2003
DE 19913683	A1	25-11-1999	AT 234477 T	15-03-2003
			WO 9949365 A1	30-09-1999
			DE 59904533 D1	17-04-2003
			EP 1071981 A1	31-01-2001
			JP 2002508583 T	19-03-2002
			US 6455429 B1	24-09-2002
US 6416908	B1	09-07-2002	NONE	
US 6375870	B1	23-04-2002	EP 1003078 A2	24-05-2000
			JP 2000147229 A	26-05-2000
			KR 2000035503 A	26-06-2000
US 5281511	A	25-01-1994	DE 4125931 A1	11-02-1993
			AT 160029 T	15-11-1997
			AU 649346 B2	19-05-1994
			AU 2072692 A	11-02-1993
			CA 2075325 A1	06-02-1993
			DE 59209004 D1	11-12-1997
			DK 526867 T3	25-05-1998
			EP 0526867 A1	10-02-1993
			ES 2109964 T3	01-02-1998
			JP 1992326 C	22-11-1995
			JP 5200456 A	10-08-1993
			JP 7012492 B	15-02-1995
			MX 9204476 A1	01-02-1993
			NO 923066 A ,B,	08-02-1993
			NZ 243818 A	26-10-1994
EP 0845710	A	03-06-1998	EP 0845710 A1	03-06-1998
			CN 1184266 A	10-06-1998